1. Record Nr. UNINA990004011410403321

Autore	Magno, Pietro
Titolo	Quinto Ennio / Pietro MAGNO
Pubbl/distr/stampa	Fasano : Schena, 1979
Descrizione fisica	287 p. ; 24 cm
Disciplina	871
Locazione	FLFBC
Collocazione	P2B-650-ENNIUS-8M.P.-1979
Lingua di pubblicazione	Italiano
Formato	Materiale a stampa
Livello bibliografico	Monografia

2. Record Nr. UNINA9910874655403321

Autore	Cui Zheng <1954->
Titolo	Nanofabrication : Principles, Capabilities and Limits / / by Zheng Cui
Pubbl/distr/stampa	Cham : , : Springer International Publishing : , : Imprint : Springer, , 2024
ISBN	9783031625466 9783031625459
Edizione	[3rd ed. 2024.]
Descrizione fisica	1 online resource (418 pages)
Disciplina	620.5
Soggetti	Microtechnology Microelectromechanical systems Nanotechnology Electronic circuits Electronics Microsystems and MEMS Electronic Circuits and Systems Electronics and Microelectronics, Instrumentation
Lingua di pubblicazione	Inglese
Formato	Materiale a stampa
Livello bibliografico	Monografia

Nota di bibliografia	Includes bibliographical references and index.
Nota di contenuto	Chapter 1. Introduction -- Chapter 2. Optical lithography -- Chapter 3. Electron beam lithography -- Chapter 4. Nanofabrication by focused ion beam -- Chapter 5. Tip-based nanofabrication -- Chapter 6. Nanoimprinting lithography -- Chapter 7. Nanoscale pattern transfer by etching -- Chapter 8. Nanoscale pattern transfer by deposition -- Chapter 9. Indirect nanofabrication -- Chapter 10. Nanofabrication by self-assembly -- Chapter 11. Applications of nanofabrication -- Chapter 9. Policing and investigating criminal activities by gangs using e-bikes, e-scooters and e-motorcycles in the United Kingdom -- Part IV-Police and Community Outreach and Collaboration. -- Chapter 10. Initiatives to improve Police – Community Collaboration and Trust -- Chapter 11. Understanding the Implementation of Community-oriented Policing in the New Zealand Police.
Sommario/riassunto	Nanofabrication: Principles, Capabilities, and Limits provides a practical guide to nanofabrication technologies and processes. It was first published in 2008 and is now in an updated third edition. The book introduces readers to the fundamentals and recent developments in nanofabrication techniques, with chapters covering optical lithography, electron beam lithography, and nanoimprinting lithography, as well as nanofabrication by focused ion beams, scanning tips, self-assembly, and nanoscale pattern transfer by etching and deposition. There is also a chapter describing various tricks that enable the fabrication of nanostructures that would otherwise be impossible using traditional methods. The unique feature of this book is that each technique introduced is not only about its capabilities but also its limits so that the readers are fully aware of the best options to choose from a toolbox of nanofabrication processes covered in the book. Contains most of the nanofabrication techniques encountered in both industrial applications and scientific research; Presents less theoretical and more practical information and examples from the author’s own work and the literature; Provides comprehensive illustrations to help understand lithography techniques using the author’s simulation programs.